

Title (en)

Method for avoiding depositions in vapour-systems

Title (de)

Verfahren zur Verhinderung von Ablagerungen in Dampfsystem

Title (fr)

Procédé pour éviter les dépôts dans un système à vapeur

Publication

EP 1245795 A3 20041006 (DE)

Application

EP 02405180 A 20020311

Priority

DE 10116034 A 20010330

Abstract (en)

[origin: EP1245795A2] Process for preventing deposition of impurities in steam systems comprises preventing the steam solubility of the impurities present in certain concentrations from being exceeded as a result of changes in temperature and/or pressure ratios within the steam system. An Independent claim is also included for a steam system for carrying out the above process. Preferred Features: The impurity is silicon dioxide. The steam system consists of steam cooling or steam injection of a gas turbine system. The temperature and/or pressure of the steam flowing through the steam system is adjusted to prevent the steam solubility of the impurities present in steam in certain concentrations from being exceeded.

IPC 1-7

F01K 21/06

IPC 8 full level

F01K 21/06 (2006.01)

CPC (source: EP US)

F01K 21/06 (2013.01 - EP US)

Citation (search report)

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- [X] US 4492083 A 19850108 - MCCABE BARKMAN C [US], et al
- [A] US 4509332 A 19850409 - BELLOWS JAMES C [US]
- [A] US 4386498 A 19830607 - LEE PANG-KAI, et al
- [A] US 2595490 A 19520506 - SCHUBRING ARTHUR C, et al

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Designated contracting state (EPC)

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DOCDB simple family (publication)

EP 1245795 A2 20021002; EP 1245795 A3 20041006; DE 10116034 A1 20021002; US 2002139118 A1 20021003; US 2006010877 A1 20060119

DOCDB simple family (application)

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